

Fabrication of low B-doped p-BaSi₂/n⁺-Si heterojunction solar cells

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[Introduction]

Semiconducting BaSi₂ has attracted attention as a future absorber-layer material for thin-film solar cells. It has an indirect band gap of approximately 1.3 eV, matching the solar spectrum, and has large absorption coefficients, reaching $3.0 \times 10^4 \text{ cm}^{-1}$ at 1.5 eV [1,2]. We have successfully fabricated n-Si/B-doped p-BaSi₂ heterojunction solar cells that achieved a conversion efficiency η of 9.9% [3]. In the work mentioned, B-doped p-BaSi₂ ($p = 2.2 \times 10^{18} \text{ cm}^{-3}$) with an optimum thickness of 20 nm acts as a hole transport layer [3]. The deterioration of η in thicker p-BaSi₂ layers is suspected due to the small minority-carrier lifetime τ of p-BaSi₂. In previous work, we confirmed that τ strongly depends on the hole concentration p of p-BaSi₂. We measured that low doped p-BaSi₂ with $p = 1.4 \times 10^{16} \text{ cm}^{-3}$ has a τ of 2.0 μs , two orders higher than sample with $p = 3.9 \times 10^{18} \text{ cm}^{-3}$ [4]. In order to utilize B-doped p-BaSi₂ as an active layer, we need to employ n-Si with lower resistivity (higher electron concentration n), so that the depletion region stretches toward the p-BaSi₂ layer, and that the device has a sufficient built-in potential at the junction.

In this work, we fabricated 300-nm-thick low-doped p-BaSi₂ on the Si substrates with various resistivities and examined the electrical properties using J - V characteristics. We then evaluated the result from the crystallinity point of view.

[Experiment]

Briefly, a 5-nm-thick template layer was grown by Ba deposition on a hot n-Si(111) substrates ($T_{\text{sub}} = 500^\circ\text{C}$, $T_{\text{Ba}} = 543^\circ\text{C}$) with resistivity ρ varied from 0.01–0.1 to 0.1–1.0 and 1.0–4.0 Ωcm . Next, Ba, Si, and B were coevaporated to form approximately 300-nm-thick a -axis-oriented B-doped p-BaSi₂ epitaxial films by MBE ($T_{\text{sub}} = 600^\circ\text{C}$, $T_{\text{Ba}} = 569^\circ\text{C}$, $R_{\text{Si}} = 2.0 \text{ \AA/s}$). The boron k-cell temperature T_{B} was set to 1000°C which correspond to a p of $1.4 \times 10^{16} \text{ cm}^{-3}$. Finally, the samples were capped with a 5 nm-thick a-Si as a passivation layer. The crystallinity of BaSi₂ was investigated by RHEED and θ -2 θ X-ray diffraction (XRD). The current density versus voltage (J - V) curves were measured under standard AM1.5, 100 mW/cm² illumination at 25°C . We also measured the FWHM of the X-ray rocking curve using BaSi₂(600) diffraction.

[Results and discussion]

Figure 1 shows the J - V characteristic of sample with different substrate ρ values. In Fig. 1, we see that the rectifying characteristics in the J - V curves gradually disappears as ρ decreases. The J - V characteristic shows a clear ohmic-like behavior when the substrate ρ is less than 0.1 Ωcm even

though the depletion region in the p layer are calculated to be less than 200 nm, thinner than the p-BaSi₂ layer thickness.

The FWHM values obtained from an ω -scan x-ray rocking curve using a BaSi₂(600) diffraction peak of sample with different substrate ρ values are plotted in Fig. 2. In Fig. 2, the degree of preferred a -axis orientation degraded as we decreased the substrate ρ . The decrease of the crystalline quality is probably one possible driving forces behind the degradation of rectifying characteristics in J - V curves. We plan to conduct TEM observations to see what happens around the p-BaSi₂/n-Si interfaces to gain further information.

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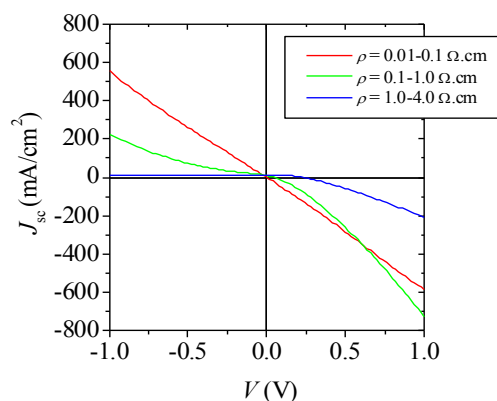


Fig. 1 J - V characteristic of p-BaSi₂/n-Si of samples with different Si substrate ρ .

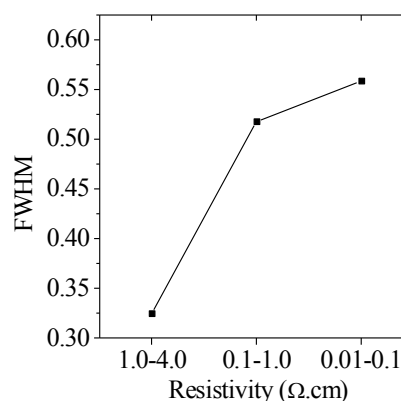


Fig. 2 FWHM values obtained from an ω -scan x-ray rocking curve of BaSi₂(600) fabricated on n-Si(111) with different ρ values.

[Reference]

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